

Abstract

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ABSTRACT OF THE DISCLOSURE

A micro-electro-mechanical system (MEMS) capacitive resonator and methods for manufacturing the same are invented and disclosed. In one embodiment, ~~the MEMS capacitive resonator~~ a method comprises ~~a semiconductor resonating member and a polysilicon electrode capacitively coupled to the semiconductor resonating member~~ forming trenches in a substrate, conformally coating the substrate with an oxide, filling the coated trenches with polysilicon, patterning the polysilicon, releasing a resonating structure derived from the substrate, and removing the conformally coated oxide.